

RUTGERS UNIVERSITY
The State University of New Jersey
College of Engineering
Bureau of Engineering Research
P. O. Box 909
Piscataway, N. J. 08854

3
NW

Final Technical Report

HIGH FIELD CONDUCTION AND SWITCHING PHENOMENA
AND MAGNETIC SPIN RESONANCE IN METAL OXIDE
THIN FILMS AND SURFACES

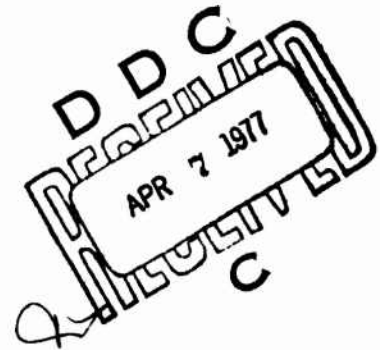
by

B. Lalevic

Department of Electrical Engineering

February 1977

Research Sponsored by the
Office of Naval Research
under
Contract N00014-76-C-0091
Task Number NR 381-013



ADA 038170

AD No.
DDC FILE COPY

Approved for Public Release; Distribution Unlimited
Reproduction in whole or in part is permitted for any
purpose of the United States Government.

SECURITY CLASSIFICATION OF THIS PAGE (When Data Entered)

REPORT DOCUMENTATION PAGE		READ INSTRUCTIONS BEFORE COMPLETING FORM
1. REPORT NUMBER 1 ✓	2. GOVT ACCESSION NO.	3. RECIPIENT'S CATALOG NUMBER
4. TITLE (and Subtitle) High Field Conduction and Switching Phenomena and Magnetic Spin Resonance in Metal Oxide Thin Films and Surfaces		5. TYPE OF REPORT & PERIOD COVERED Final Technical Report PERFORMING ORG. REPORT NUMBER for period ending 31 Oct 76 CONTRACT OR GRANT NUMBER
7. AUTHOR(s) Bogoljub Lalevic		15. NO. 14-76-C-0091
9. PERFORMING ORGANIZATION NAME AND ADDRESS Department of Electrical Engineering, College of Engineering, Rutgers University, P.O. Box 909, Piscataway, N.J. 08854		10. PROGRAM ELEMENT, PROJECT, TASK AREA & WORK UNIT NUMBERS NR 381-013
11. CONTROLLING OFFICE NAME AND ADDRESS Office of Naval Research (Code 471) Arlington, Va. 22217		12. REPORT DATE 12 11 P. 13. NUMBER OF PAGES
14. MONITORING AGENCY NAME & ADDRESS (if different from Controlling Office) (11 Feb 77)		15. SECURITY CLASS. (of this report) Unclassified 15a. DECLASSIFICATION/DOWNGRADING SCHEDULE
16. DISTRIBUTION STATEMENT (of this Report) Approved for public release; distribution unlimited.		
17. DISTRIBUTION STATEMENT (of the abstract entered in Block 20, if different from Report)		
18. SUPPLEMENTARY NOTES		
19. KEY WORDS (Continue on reverse side if necessary and identify by block number) Conduction Mechanism Poole-Frenkel Conduction MIM Structure Dielectric Dispersion Polaron Hopping Double Injection Model Dielectric Breakdown Non-Adiabatic Hopping R.F. Oscillations Switching Mechanism Debye Dispersion		
20. ABSTRACT (Continue on reverse side if necessary and identify by block number) Investigation was performed on transport, dielectric, switching and optical properties of thin amorphous and polycrystalline films of a series of transition metal and other oxides films. The conduction and dielectric dispersion mechanisms were unambiguously identified for each oxide studied in the parent metal-oxide-parent metal configuration. The switching phenomena and the observed RF oscillations in the negative resistance region were fully explained by the double injection model. Stable and → next page		

DD FORM 1 JAN 73 1473

EDITION OF 1 NOV 65 IS OBSOLETE
S/N 0102-LF-014-6601

SECURITY CLASSIFICATION OF THIS PAGE (When Data Entered)

40715

SECURITY CLASSIFICATION OF THIS PAGE (When Data Entered)

reproducible switching devices were fabricated and the properties of important switching parameters studied as a function of composition temperature and applied voltage.

SECURITY CLASSIFICATION OF THIS PAGE (When Data Entered)

TABLE OF CONTENTS

	<u>Page</u>
I Preface	1
II Summary of Results	1
II-1 General Review	1
II-2 Transport Mechanism	2
II-3 Dielectric Dispersion	3
II-4 Switching Mechanism	4
II-5 Switching Devices	4
II-6 Optical and Electrical Properties of Other Oxides	4
III Personnel	5
IV Ph.D. Dissertations	5
V Publications	5
VI Technical Presentations	7

ACCESSION for

NTIS ☒ White Section
DSC ☐ Bull Section

UNANNOUNCED
JUSTIFICATION

BY
DISTRIBUTION/AVAILABILITY CODES

Dist. Avail. and/or SPECIAL

A

I PREFACE

This final report briefly reviews the results covering a three year period ending Oct. 31, 1976. The principal objectives of the research program were to study high field conduction properties, dielectric dispersion and switching phenomena in amorphous and polycrystalline metal oxide thin films and their surfaces. Another objective was to improve the switching performance of thin film transition metal oxide devices.

The detailed results of this research program were presented in journal articles, national and international meetings, Ph.D. dissertations and patent applications. As a result of this program 18 papers were published and 4 papers are under preparation or in the submission stage, 8 presentations were made at different meetings, 4 Ph.D theses completed and 2 applications for patentable inventions were made. The list of published papers and other publications is presented in this report.

II SUMMARY OF RESULTS

II-1 General Review

An investigation was performed of transport, dielectric and switching properties of amorphous and polycrystalline thin films of NiO , $\text{NiO}(\text{Li})$, CoO , $\text{CoO}(\text{Li})$, Nb_2O_5 , TiO_2 and of the optical and electrical properties of SiO_2 , Al_2O_3 , WC and their layered structures with different noble and transition metals.

Experimental results on transport properties of CoO , $\text{CoO}(\text{Li})$, Nb_2O_5 and TiO_2 are found to be in excellent agreement with the generalized theory of the Poole-Frenkel field-assisted emission mechanism. The theory of small polaron hopping mechanism rendered the best agreement with the results of measurements on transport properties of NiO and $\text{NiO}(\text{Li})$ polycrystalline films.

Dielectric dispersion was found to be either due to the Debye type of thermally activated hopping mechanism, or to adiabatic hopping from the uncorrelated sites. Relaxation times of different dispersion mechanisms were determined by the use of Cole-Cole or Scaiffe plots. The dielectric breakdown process is fully explained in terms of a formation of four sequential conduction states.

The mechanism of switching from high to low resistance states and of the current controlled negative resistance region was explained on

the basis of I-V characteristics, Balberg's double pulse test and the observed R-f relaxation oscillation in the negative resistance region. The analysis of the above experiments was found to be in excellent agreement with Lampert's double injection theory of switching mechanism. The work on surface switching has shown that devices with a surface electrode configuration resulted in better switching devices. A model and preliminary calculations were made for this type of a device.

Results on the optical, electric and mechanical properties of thin films of SiO_2 , Al_2O_3 and WC_4 and their layered structures with noble and transition metals, have shown considerable improvement in mechanical properties and drastic changes in the optical properties of cosputtered metal-oxide films.

II-2 Transport Mechanism

The I-V-T relationship for a semicrystalline material is given in the generalized Poole-Frenkel field-assisted conduction mechanism by the following expression:

$$I = I_0 (kT)^4 (\beta_{PF})^{-2} \exp(-E_i/kT) \alpha^2 \sinh \alpha$$

where $\beta = \frac{e^{3/2}}{(\pi \epsilon d)^{1/2}} \frac{1}{kT}$, E_i is the ionization energy and

$$\alpha = \left(\frac{\beta_{PF}}{kT} \right) \left(\frac{V}{d} \right)^{1/2}$$

A plot of $IT^{-4} \exp(E_i/kT)$ vs $V^{1/2}/T$ should produce an $\alpha^2 \sinh \alpha$ curve. This type of a plot was found to be in excellent agreement with the measurements on amorphous and polycrystalline films of Nb_2O_5 [1,5,11] CoO and CoO(Li) [2] and TiO_2 [10]. The ionization energy E_i is found to vary between 0.145 eV for TiO_2 to 0.27 eV for Nb_2O_5 .

The I-V and G-V measurements on thin NiO and NiO(Li) films are found to be in agreement with the following expression for a polaronic hopping conduction mechanism [3,4]:

$$G = \frac{ne^2 a^2 \epsilon'}{kT} v_0 \left[1 + \frac{E^2}{2} \left(\frac{ea\epsilon'}{2kT} \right)^2 + \dots \right] \exp \left(- \frac{W_H}{kT} \right)$$

where n is the free carrier concentration, $a(4.1\text{\AA})$ is the lattice constant, $\epsilon' = \frac{E_{\text{local}}}{E} = \frac{\epsilon + 2}{3}$, $\nu \approx 10^{-12}$ sec is the hopping frequency, $W_H = 0.3$ eV is the activation energy for polaron hopping and E is the applied field. The experimental plots of G vs V^2 are found to be in agreement with the above relation.

II-3 Dielectric Dispersion

Dielectric dispersion and polarization are found to be due to hopping of charge carriers at higher frequencies and to interfacial polarization and blocking electrode effects at low frequencies. The observed frequency dependence of ac conductivity ($\sigma(\omega)$) $\sigma(\omega) \approx \omega$ at higher frequencies [8,10] is in agreement with the theory of non-correlated hopping of charge carriers where:

$$\sigma(\omega) = \left(\frac{\pi^3}{96}\right) N^2(E_F) kT a r_\omega^4 e^2 \omega$$

Here $N(E_F)$ is the probability density of localized states at the Fermi level ($\text{cm}^{-3} \text{eV}^{-1}$), r_ω is the separation between a pair of localized states ($r_\omega = a \ln(\nu_0/\omega)$ where $\nu_0 \approx 10^{12} \text{sec}^{-1}$) and a is the lattice constant. The values of $N(E_F)$ ranged from $1.5 \times 10^{19} \text{cm}^{-3} \text{eV}^{-1}$ for Nb_2O_5 [8] to $7 \times 10^{19} \text{cm}^{-3} \text{eV}^{-1}$ for TiO_2 [10] and r_ω from $49\text{\AA}$ to $65\text{\AA}$, respectively.

In the intermediate frequency range, the ac conductivity varies with frequency as $\sigma(\omega) \propto \omega^n$ where $0.75 < n < 0.8$ [2,8,16]. This corresponds to the theoretically predicted relationship for non-adiabatic hopping as given by:

$$R_e \sigma(\omega) \propto (14.8 - \frac{1}{2} \ln \omega)^4$$

A plot of the right-hand side of the above relation shows that $\sigma(\omega) \propto \omega^{0.8}$ which is in close agreement with experimental results.

Relaxation times at low frequencies were obtained from the Cole-Cole plots when modified Debye relations were used in the form [2.8]:

$$\epsilon^* = \epsilon_\infty + \frac{\epsilon_0 - \epsilon_\infty}{(1+j\omega\tau)^\beta}$$

with $\epsilon_1 - \epsilon_\infty = (\epsilon_0 - \epsilon_\infty)(\cos\phi)^\beta \cos\beta\phi$

$$\epsilon_2 = (\epsilon_0 - \epsilon_\infty)(\cos\phi)^\beta \sin\beta\phi$$

Here $\tan\phi = \omega\tau$ and $\omega\tau_0 = \tan\theta/\beta$, where $\theta = \tan^{-1}(\frac{\epsilon_2}{\epsilon_1 - \epsilon_\infty})$; τ_0 is the relaxation time and $0 < \beta < 1$. The values for relaxation times ranged from 2×10^{-2} sec [8] to 1.6×10^{-4} sec [2].

II-4 Switching Mechanism

Experimental results on switching mechanisms are found to be in excellent agreement with Lampert's theory of double injection mechanism (17). The I-V characteristics show an initial linear increase of I with increasing V followed by an $I \propto V^2$ relation on increasing the applied voltage. Following the negative resistance region I again becomes proportional to V^2 , which is in complete agreement with Lampert's model.

Experiments on Balberg's double pulse method for testing the switching mechanism rules out the thermal runaway model and was in complete agreement with Lampert's model. The analysis of the observed RF oscillations in the negative resistance region (12) was found to be in agreement with the above model.

II-5 Switching Devices

Stable and reproducible switching devices were made of thin transition metal oxide films that could support an input power greater than 2 watts with a device lifetime greater than 10^8 switching cycles. The significant and novel features observed in the switching process are the following [7,8,9,11]: a) Switching occurs within < 2.5 mV for triggering pulses in the range 2-4V; b) the delay time τ_d decreases exponentially with increasing applied voltage; c) recovery time τ_r is 20 n sec and d) the proper switching time τ_s is less than 3 n sec.

Switching devices with the surface electrode configuration were studied using NiO and NiO(Li) polycrystalline thin film devices. These devices have shown an increased lifetime by a factor of 10^3 switching cycles due to the improved heat exchange with the substrate.

A surface switching electrode configuration, similar to that of a unijunction transistor was studied and it was calculated that the delay time can be reduced below 10^{-9} sec. The experiments, however, were not carried out due to the cessation of the program and the lack of IC facilities.

II-6 Optical and Electrical Properties of Other Oxides

These studies were performed on thin films of SiO_2 , Al_2O_3 and

WC₄, on the metal-dielectric thin film configuration and on the thin dielectric films codeposited with metals. Noble and transition metals were used in layered structures and codeposition studies. Vastly improved optical and electrical properties were observed in the layered and codeposited films. Since numerous compositions were studied it would be difficult to enumerate them in a report and the details can be found in the references 13, 14 and 15.

III PERSONNEL

Following is a list of professional personnel who participated in the investigations.

Investigators:

N. Fuschillo, died on Oct. 15, 1974, Professor of Electrical Engineering.

B. Lalevic, Associate Research Professor of Electrical Engineering.

Guest Scientist:

Dr. Bekir Kuliyeu, Azerbaijan Academy of Science.

Graduate Students:

N.K. Annamalai, Ph.D.; B. Leung, Ph.D.; W. Slusark, Ph.D.;
G. Taylor Ph.D.; W. Wang, M.S.

IV - Ph.D. DISSERTATIONS

1. N. K. Annamalai, "Transport, Dielectric and Switching Properties of Nb₂O₅ Thin Films in the Device Configuration of Nb - Nb₂O₅ - Nb" Ph.D. Thesis, Rutgers University, March, 1974.

2. B. Leung, "Transport, Dielectric and Switching Properties of NiO and NiO(Li) Thin Films in the Device Configuration Ni - NiO - Ni", Ph.D. Thesis, Rutgers University, January, 1976.

3. G. Taylor, "Switching and Conduction Mechanisms, Dielectric Dispersion, and RF Oscillations in Polycrystalline Thin Films of TiO₂", Ph.D. Thesis, Rutgers University, June, 1976.

4. W. Slusark, "Dielectric Dispersion, Transport and Switching Properties of Thin Polycrystalline Films of Nb₂O₅", Ph.D. Thesis, Rutgers University, May, 1976.

V - PUBLICATIONS

The following papers were published as a result of research on the ONR contract:

1. "Non-linear Transport and Switching Properties of Transition Metal Oxides," N. Fuschillo and B. Lalevic, Jap.J. Appl. Phys. 13-Suppl. 2, part 1, 817 (1974).
2. "Transport and Dielectric Properties of Thin Polycrystalline Films of CoO," B. Lalevic, N. Fuschillo, B. Kuliyeu and W. Wang, Appl. Phys. 5, 127 (1974).

3. "High Field Transport in NiO and $\text{Ni}_{1-x}\text{Li}_x\text{O}$ Thin Films,"
B. Lalevic, N. Fuschillo and B. Leung, Solid State Electronics 19,
394 (1976).
4. "Electrical Conduction and Dielectric Breakdown in Crystalline NiO
and $\text{NiO}(\text{Li})$ Films," with N. Fuschillo, B. Lalevic and B. Leung,
J. Appl. Phys. 46, 310 (1975).
5. "Atomic Implantation of Nb in Amorphous Nb_2O_5 Films by RF Sputter-
ing," B. Lalevic, N. Annamalai and N. Fuschillo, J. Vac. Sci.
Technol. 12, 52 (1975).
6. "Hopping Conduction in Amorphous Nb_2O_5 Films," N. Annamalai and
B. Lalevic, J. Non-Cryst. Solids, 20, 651 (1976).
7. "Switching Phenomena and Dielectric Breakdown in Amorphous
 Nb_2O_5 Films," with N. Annamalai, B. Lalevic, N. Fuschillo and
W. Slusark, J. Non-Cryst. Solids, 22, 85, (1976).
8. "Dielectric Properties of Nb_2O_5 Films," with N. Annamalai,
B. Lalevic and N. Fuschillo, Thin Solids Films, 30, 141 (1975).
9. "Switching in Nb- Nb_2O_5 -Nb Devices with Doped Nb_2O_5 Amorphous Films,
B. Lalevic, W. Slusark and N. Fuschillo, IEEE Trans. Electron
Devices ED-22, 965 (1975).
10. "Electrical Conduction in Thin Polycrystalline TiO_2 Films,"
B. Lalevic and G. Taylor, J. A-pl. Phys. 46, 3208 (1975).
11. "Switching Processes and Dielectric Breakdown in Polycrystalline
 Nb_2O_5 Films," B. Lalevic and W. Slusark, J. of Elec. Materials,
5, 531 (1976).
12. "RF Relaxation Oscillations in Polycrystalline TiO_2 Films,"
G. Taylor and B. Lalevic, Solid State Electronics, 19, 669 (1976).
13. "Properties of Metal-Dielectric Co-Deposited Films," G. Taylor and
W. Slusark, Thin Solid Films, accepted to be published in Sept.-
Oct. 1976 Volume.
14. "Optical Mechanical and Corrosion Properties of Metal-Metal and
Metal-Dielectric Thin Layered Films," W. Slusard, B. Lalevic and
G. Taylor, Thin Solid Films, accepted to be published in Sept.-
Oct. 1976 volume.
15. "Hard Transparent Dielectric Coatings," G. Taylor, B. Lalevic and
W. Slusark, Thin Solid Films, accepted to be published in Sept.-
Oct. 1976 volume.
16. "Schottky-Barriers Effects on the Dielectric Behavior of the
Nb- Nb_2O_5 -Nb System," B. Lalevic and N. Annamalai, Physica Status
Solidi, 37, K 177 (1976).
17. "Dielectric Dispersion and Polarization Effects in Thin Transition
Metal Oxide Films," B. Lalevic, N. Annamalai, B. Leung, G. Taylor
and W. Slusark, Vacuum, accepted.
18. "Mechanism of Threshold Switching in TiO_2 Films," G. Taylor and
B. Lalevic, J. Appl. Phys., April (1977).

VI TECHNICAL PRESENTATIONS:

N. Fuschillo and B. Lalevic, 6th Inter. Vacuum Congress, Kyoto, Japan, April 1974.

N. Fuschillo, B. Lalevic and N. Annamalai, Proc. 21st Nat. Symp. Am. Vacuum Soc., Anaheim, Calif., Oct. 8, 1974.

N. Fuschillo, B. Lalevic, W. Slusark and A. Delahoy, Proc. 31st Nat. Symp. Am. Vacuum Soc., Anaheim, Calif., Oct. 8, 1974.

B. Lalevic and W. Slusark, 17th Inter. Annual Conf. on Prop. of Electronic Mat., Princeton, NJ, Aug. 25-27, 1975.

B. Lalevic, G. Taylor and W. Slusark, 14th Inter. Conf. on Metallurgical Coatings, San Francisco, Calif., April 5-7, 1976.

G. Taylor, B. Lalevic and W. Slusark, 14th Inter. Conf. on Metallurgical Coatings, San Francisco, Calif., April 5-7, 1976.

W. Slusark, B. Lalevic and G. Taylor, 14th Inter. Conf. on Metallurgical Coatings, San Francisco, Calif., April 5-7, 1976.

B. Lalevic, N. Annamalai, B. Leung, G. Taylor and W. Slusark, Inter. Symposium on Thin Films, Uppsala, Sweden, Aug. 31-Sept. 3, 1976.

SEPTEMBER 1976

DISTRIBUTION LIST FOR ONR PHYSICS PROGRAM OFFICE
UNCLASSIFIED CONTRACTS

Director Defense Advanced Research Projects Agency Attn: Technical Library 1400 Wilson Blvd. Arlington, Virginia 22209	3 copies
Office of Naval Research Physics Program Office (Code 421) 800 North Quincy Street Arlington, Virginia 22217	3 copies
Office of Naval Research Assistant Chief for Technology (Code 200) 800 North Quincy Street Arlington, Virginia 22217	1 copy
Naval Research Laboratory Department of the Navy Attn: Technical Library Washington, D. C. 20375	3 copies
Office of the Director of Defense Research and Engineering Information Office Library Branch The Pentagon Washington, D. C. 20301	3 copies
U. S. Army Research Office Box CM, Duke Station Durham, North Carolina 27706	2 copies
Defense Documentation Center Cameron Station (TC) Alexandria, Virginia 22314	12 copies
Director, National Bureau of Standards Attn: Technical Library Washington, D. C. 20234	1 copy
Commanding Officer Office of Naval Research Branch Office 536 South Clark Street Chicago, Illinois 60605	3 copies

San Francisco Area Office Office of Naval Research 760 Market Street, Room 447 San Francisco, California 94102	3 copies
Office of Naval Research Code 102 1P (ONR/L) 800 North Quincy Street Arlington, Virginia 22217	6 copies
Air Force Office of Scientific Research Department of the Air Force Washington, D. C. 22209	1 copy
Commanding Officer Office of Naval Research Branch Office 1030 East Green Street Pasadena, California 91101	3 copies
Commanding Officer Office of Naval Research Branch Office 495 Summer Street Boston, Massachusetts 02210	3 copies
Director U. S. Army Engineering Research and Development Laboratories Attn: Technical Documents Center Fort Belvoir, Virginia 22060	1 copy
ODDR&E Advisory Group on Electron Devices 201 Varick Street New York, New York 10014	3 copies
New York Area Office Office of Naval Research 715 Broadway, 5th Floor New York, New York 10003	1 copy
Air Force Weapons Laboratory Technical Library Kirtland Air Force Base Albuquerque, New Mexico 87117	1 copy
Air Force Avionics Laboratory Air Force Systems Command Technical Library Wright-Patterson Air Force Base Dayton, Ohio 45433	1 copy

Lawrence Livermore Laboratory Attn: Dr. W. F. Krupke University of California P. O. Box 808 Livermore, California 94550	1 copy
Harry Diamond Laboratories Technical Library Connecticut Ave. at Van Ness, N. W. Washington, D. C. 20008	1 copy
Naval Air Development Center Attn: Technical Library Johnsville Warminster, Pennsylvania 18974	1 copy
Naval Weapons Center Technical Library (Code 753) China Lake, California 93555	1 copy
Naval Training Equipment Center Technical Library Orlando, Florida 32813	1 copy
Naval Underwater Systems Center Technical Library New London, Connecticut 06320	1 copy
Commandant of the Marine Corps Scientific Advisor (Code RD-1) Washington, D. C. 20380	1 copy
Naval Ordnance Station Technical Library Indian Head, Maryland 20640	1 copy
Naval Postgraduate School Technical Library (Code 0212) Monterey, California 93940	1 copy
Naval Missile Center Technical Library (Code 5632.2) Point Mugu, California 93010	1 copy
Naval Ordnance Station Technical Library Louisville, Kentucky 40214	1 copy

Commanding Officer 1 copy
Ocean Research & Development Activity
National Space Technology Laboratories
Bay St. Louis, Mississippi 39520

Naval Explosive Ordnance Disposal Facility 1 copy
Technical Library
Indian Head, Maryland 20640

Naval Electronics Laboratory Center 1 copy
Technical Library
San Diego, California 92152

Naval Undersea Center 1 copy
Technical Library
San Diego, California 92132

Naval Surface Weapons Center 1 copy
Technical Library
Dahlgren, Virginia 22448

Naval Ship Research and Development Center 1 copy
Central Library (Code L42 and L43)
Bethesda, Maryland 20084

Naval Surface Weapons Center 1 copy
Technical Library
Silver Spring, Maryland 20910

Naval Avionics Facility 1 copy
Technical Library
Indianapolis, Indiana 46218

Office of Naval Research
Branch Office
495 Summer Street
Boston, MA 02210
Chief Scientist:

Dr. Arnst L. Powell
Phone: 617 542-5117

Office of Naval Research
Area Office, New York
715 Broadway - Fifth Floor
New York, NY 10003
Chief Scientist:

Dr. Irving Rowe
Phone: 212 264-8081

The ONR Resident Representative
Princeton, NJ is:

J. J. Sladovich
Room 103, Plasma Physics Lab "B"
James Forrestal Campus
Princeton University
Princeton, New Jersey 08540
Phone: 609 452-9140
or 452-5090